

**AMENDMENTS TO THE SPECIFICATION:**

Please add the following new paragraph after paragraph [0005]:

[0006] A preferred embodiment of a component of a plasma processing apparatus comprises a first part including an attachment surface and an exposed surface adapted to be exposed to an interior of a plasma processing chamber; a second part including a first surface spaced from a second surface, the first surface being bonded to the attachment surface of the first part, the second part including axially extending apertures extending between the first surface and the second surface, each of the apertures including a first portion opening in the first surface and a second portion opening in the second surface, the first portion being wider in a transverse direction than the second portion; and fastener members located in the second portions of the apertures. The first part can be a showerhead electrode and the second part can be a backing plate.